



#1013DS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 1756
Examiner: Kathleen Duda

RECEIVED
JAN 29 2003
TC 1700

In re PATENT APPLICATION of:

Applicant(s) : Minoru WATANABE

Appln. No. : 10/025,783

Filed : December 26, 2001

For : METHOD AND APPARATUS FOR
FORMING RESIST PATTERN

Atty. Dkt. : MAE 223 C1

INFORMATION
DISCLOSURE
STATEMENT

Commissioner for Patents
Washington, D.C. 20231

Sir:

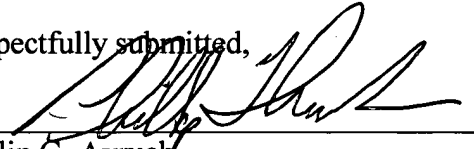
This is an information disclosure statement submitted in compliance with the timing requirements of 37 C.F.R. §1.97(b)(1).

Attached are copies of four U.S. patent documents. The patents are listed on the attached Form PTO-1449.

Since this Information Disclosure Statement is being filed with the RCE application, no certification or fee is required, and the requirements of 37 C.F.R. §§1.97 and 1.98 are deemed to be fully met as to the document submitted. Consideration of the submitted document is respectfully requested.

Respectfully submitted,

January 24, 2003


Phillip G. Avruch
(Registration No. 46,076)
Rabin & Berdo, P.C.
Customer No. 23995
(202) 371-8976 (telephone)
(202) 408-0924 (facsimile)

PGA:tlc